

EHS NA TC Chapter Meeting Minutes
 NA Meeting Spring 2016
 Thursday, November 5, 2015, 09:00 AM - 3:00 PM
 SEMI HQ, San Jose, CA

Next Committee Meeting

Thursday, July 14, 2016, San Francisco, CA in conjunction with SEMICON West. Check www.semi.org/standards for the latest update.

SEMI Staff

Kevin Nguyen – SEMI HQ
 James Amano – SEMI HQ
 Sanjay Baliga – SEMI EHS Division

Presiding chair – Sean Larsen (Lam Research)

Table 1 – Attendees

<i>Last Name</i>	<i>First Name</i>	<i>Company</i>
Belk	Bill	WB Environmental Solutions
Claes	Brian	Lam Research
Crane*	Lauren	KLA-Tencor
DeFrain*	Steve	ESTEC Solutions
Ergete	Nigusu	ESTEC Solutions
Evanston	Chris	Salus Engineering
Green	Paul	Ultratrech
Greenberg	Cliff	Nikon Precision
Hoshi	George	Tokyo Electron
Johnson	J.D.	Advanced Energy
Karl	Ed	Applied Materials
Layman	Curt	Seagate
Macklin*	Ron	Macklin & Associates
Mashiro	Supika	Tokyo Electron
Petry*	Bill	GlobalFoundries
Planting	Bert	ASML
Pochon	Stephan	TUV
Rai	Sunny	Intertek
Sklar	Eric	Safety Guru
Tsuru	Mark	Tokyo Electron
Visty	John	Salus Engineering

*attended via teleconference

Table 2 – Task Force Changes

Flow Limitation Task Force was disbanded
S27 Revision Task Force was disbanded

Table 3 – Ballots Summary

<i>Document #</i>	<i>Document Title</i>	<i>Committee Action</i>
5970	Line Item Revisions to SEMI S14, Safety Guidelines for Fire Risk Assessment and Mitigation for Semiconductor Manufacturing Equipment	
	Line Item 1 - Changes to Terminology to Align with SEMI S10	Passed with editorial change
	Line Item 2 - Change “Grouping” to “Group” to Align with SEMI S10	Passed as balloted
	Line Item 3 - Changes to Risk Categories to Align with SEMI S10	Passed as balloted
5969	Line Item Revisions to SEMI S2-0715, Environmental, Health, and Safety Guideline for Semiconductor Manufacturing Equipment (Re: Fire Protection)	
	Line Item 1 - Addition of a Delayed Revisions Section Related to Work at Elevated Locations and Design Criteria for Platforms, Steps, and Ladders	Failed, to be reballoted
	Line Item 2 - Restructuring of portions of Section 14	Passed as balloted
4683H	Line Item Revision to SEMI S2-0715, Environmental, Health, and Safety Guideline for Semiconductor Manufacturing Equipment. Delayed Revisions Related to Chemical Exposure	
	Line Item 1 - Delayed Revisions Related to Chemical Exposure Criteria	Failed, to be reballoted

Table 4 – Authorized Ballots

<i>#</i>	<i>When</i>	<i>SC/TF/WG</i>	<i>Details</i>
5761A	cycle 5-2016	Energetic Materials EHS Task Force	New Standard: Safety Guideline for Use of Energetic Materials in Semiconductor R&D and Manufacturing Processes
4683I	cycle 5-2016	S2 Chemical Exposure Task Force	Line Item Revision to SEMI S2-0715, Environmental, Health, and Safety Guideline for Semiconductor Manufacturing Equipment. Delayed Revisions Related to Chemical Exposure
5969A	cycle 5-2016	Fire Protection Task Force	Line Item Revision to SEMI S2-0715, Environmental, Health, and Safety Guideline for Semiconductor Manufacturing Equipment (Re: Fire Protection)
5681	cycle 5-2016	S6 Revision Task Force	Line Item Revision to SEMI S6, EHS Guideline for Exhaust Ventilation of Semiconductor Manufacturing Equipment
5917	cycle 5-2016	Ergonomics Task Force	Line Item Revisions to SEMI S8, Safety Guidelines for Ergonomics Engineering of Semiconductor Manufacturing Equipment. Addition of reference to a manual material-handling guide in SEMI-S8, Appendix 2, Lifting, Strength, and Materials Handling

Table 5 – Authorized Activities

<i>#</i>	<i>Type</i>	<i>SC/TF/WG</i>	<i>Details</i>
5996	SNARF	Ergonomics Task Force	Line Item Revision to S8, Safety Guideline for Ergonomics Engineering of Semiconductor Manufacturing Equipment

Note: SNARFs and TFOFs are available for review on the SEMI Web site at:

<http://downloads.semi.org/web/wstdsbal.nsf/TFOFSNARF>

Table 6 – Previous Meeting Actions Items

<i>Item #</i>	<i>Assigned to</i>	<i>Details</i>	<i>Status</i>
2015Nov #01	Kevin Nguyen	To inform Taiwan staff for possible participation in doc. 5681, Line Item Revision to SEMI S6, EHS Guideline for Exhaust Ventilation of Semiconductor Manufacturing Equipment	Completed
2015Nov #02	Kevin Nguyen	To request Taiwan EHS to provide presentation materials in English in advance for NA feedback.	Completed
2015Nov #03	Kevin Nguyen	To remind NA EHS co-chairs to place Flow Limitation TF disbandment the agenda for the next meeting.	Completed

Table 7 – New Actions Items

<i>Item #</i>	<i>Assigned to</i>	<i>Details</i>
2016April #01	Kevin Nguyen	To request SEMI EHS division to coordinate with standards and limit EHS Division activities to just one day of meeting at SEMICON West
2016April #02	Kevin Nguyen	To check if SNARF 4975 (Line Item Revision to SEMI S6, EHS Guideline for Exhaust Ventilation of Semiconductor Manufacturing Equipment (Line item revisions for addressing gas detectors and other concerns)) was granted for a 1 year extension.

1.0 Call to Order

Sean Larsen called the meeting to order and welcomed everyone who attended. A round of self-introduction was made. All SEMI standards meetings are subjected to SEMI Anti-Trust Reminder and Guidelines concerning Patentable Technology. SEMI Regulations now require all attendees to be members of SEMI standards. Membership enrollment is at www.semi.org/standardsmembership. The agenda was reviewed and approved.

2.0 Review and Approval of Meeting Minutes from NA Fall Meeting, San Jose, CA, Nov. 5, 2015

Minutes were reviewed. Several changes were recommended by Eric Sklar.

Motion: To accept the minutes as amended.

By / 2nd: Bert Planting/John Visty

Discussion: None

Vote: 8/0. Motion passed

[Attachment – 1, EHSNAMeetingMinutes20151105rev1](#)

3.0 Ballots Review

3.1 *Doc. 4683H, Line Item Revision to SEMI S2-0715, Environmental, Health, and Safety Guideline for Semiconductor Manufacturing Equipment. Delayed Revisions Related to Chemical Exposure*

- Line Item 1 - Delayed Revisions Related to Chemical Exposure Criteria
 - The ballot failed review and was authorized to resubmit for cycle 5-2016 for review at the next meeting. See attachment for ballot adjudication.

[Attachment – 2, 4683H-LI1 Compiled Resp_TF inputs040516](#)

3.2 *Doc. 5969, Line Item Revisions to SEMI S2-0715, Environmental, Health, and Safety Guideline for Semiconductor Manufacturing Equipment (Re: Fire Protection)*

- Line Item 1 - Addition of criteria to determine which method of assessing fire risk is to be used.
 - The ballot failed review and was authorized to resubmit for cycle 5-2016 for review at the next meeting. See attachments for ballot adjudication.
- Line Item 2 - Restructuring of portions of Section 14
 - The ballot passed as balloted. See attachments for ballot adjudication.

[Attachment – 3, 5969 LI1+2_CompiledResponses_es07apr16a](#)

[Attachment – 4, 5969ProceduralReview](#)

3.3 *Doc. 5970, Line Item Revisions to SEMI S14, Safety Guidelines for Fire Risk Assessment and Mitigation for Semiconductor Manufacturing Equipment*

- Line Item 1 - Changes to Terminology to Align with SEMI S10
 - The ballot passed with editorial changes. See attachments for ballot adjudication.

- Line Item 2 - Change “Grouping” to “Group” to Align with SEMI S10
 - The ballot passed as balloted. See attachments for ballot adjudication.
- Line Item 3 - Changes to Risk Categories to Align with SEMI S10
 - The ballot passed as balloted. See attachments for ballot adjudication.

[Attachment – 5, 5970_L1..3_CompiledResponses_es07apr16a](#)

[Attachment – 6, 5970ProceduralReview](#)

4.0 Subcommittee & Task Force Reports

4.1 *Manufacturing Equipment Safety Subcommittee (MESSC)*

Cliff Greenberg reported. Highlight of slides are as follows:

- From Bert, ASML:
 - Is S10 just EHS-focused or beyond?
- Should we have a kind of spin-off for non-related EHS issues (e.g an RI?)
 - Machine and facility “damage” issues
 - Product? Difficult for ME supplier to make those decisions
- Split MESSC into two time slots so one could be reallocated based on need?
- Move summer meetings to SEMI HQ the week after SEMICON?
- EHS division time expectations in SanFran vs Standards meeting needs
 - Discussion:
 - Brian Claes: Required to hold Standards meetings at SEMICON?
 - Eric Sklar: SEMICONs used to draw a large number of device manufacturers. However, it is no longer the case.
 - Paul Green: For budgeting reason, upper managements are more likely to approve for travelling to SEMICON event versus an offsite meeting.
 - Supika Mashiro: Big companies should dedicate manpower to attend both EHS Division and Standards meetings if they felt it is important.
 - Cliff Greenberg: Some companies have that luxury, while others are not.
 - Lauren Crane: For certain individuals, their job descriptions require covering both product design and EHS regulations.
 - Chris Evanston: EHS Division appears to not coordinating with Standards. Having two days of meetings for EHS Division will impact Standards meetings.

Motion: To request SEMI EHS division to coordinate with standards and to limit EHS Division activities to just one day of meeting at SEMICON West

By / 2nd: Chris Evanston/Bert Planting

Discussion: Ron Macklin suggested to check with Karen Salvala, who is the VP of SEMI.

Supika Mashiro said that she had a conversation with Jonathan Davis, Sanjay Baliga’s boss. Per Supika, he said there are too many EHS Standards meetings at SEMICON West. It is hard to avoid.

Vote: 9/0. Motion passed

[Attachment – 7, 2016 Spring MESSC minutes](#)

4.2 *S6 Exhaust Ventilation Revision TF*

John Visty reported the TF made significant progress on line 1 (definition change to flow/Q) ballot. The ballot will be cleaned up and issued separately in cycle 5. A technical editor is needed for reviewing the ballot prior to submitting to SEMI.

Line item 2 has minimal progress. For line item 3, there was not enough time to discuss.

[Attachment – 8, S6 Task Force_GH-040716](#)

4.3 *S2 Non-ionizing Radiation TF*

Same as last meeting, Sean Larsen reported the TF is working on doc. 5625, Line Item Revisions to SEMI S2, Environmental, Health, and Safety Guideline for Semiconductor Manufacturing Equipment. Delayed Revisions Related to Non-Ionizing Radiation.

4.4 *S2 Seismic Protection Liaison TF*

Lauren Crane reported Japan is working on draft doc. 5556B, Line Item Revisions to SEMI S2-0715, Environmental, Health, and Safety Guideline for Semiconductor Manufacturing Equipment (Revisions Related to Section 19 Seismic Protection). The North American Liaison TF met several times by teleconferences and provided the requested advice. The ballot is planned for cycle 4-2016 for review in the summer meeting at SEMI Japan office.

[Attachment – 9, S2 Seismic Liaison TF Report Spring 2016 Rev 1](#)

4.5 *S23 Global TF*

George Hoshi reported and provided the progress for doc. 5947A, Revision to SEMI S23-0813, with title change to "Guide for Energy, Utilities and Materials Use Efficiency of Semiconductor Manufacturing Equipment". The ballot will be issued for cycle 4-16 for review in June 2016 Japan meeting.

[Attachment – 10, S23 GTF Report US Spring meetings 2016](#)

4.6 *S10 Revision TF*

Bert Planting reported progress made since the Fall meetings. Alignment of issues should be addressed for next ballot.

- Severity table proposal
 - Limit to Human and environmental impact
 - Update with clear limits

- Adding an RI with a complete risk assessment include expanding severities to damage due to fire, equipment damage, facility loss and maybe loss of customer product. Risk assessment was improved (3 steps in likelihood).

[Attachment – 11, S10 taskforce report Spring 2016 MoM](#)

4.7 *S27 Report Contents TF*

Chris Evanston reported S27 *Safety Guideline for the Contents of Environmental, Safety, and Health (ESH) Evaluation Reports* was initially sent out for reapproval ballot. There were negatives. The TF has no desire to work on revision and took a vote on what to do with S27. The majority was in favor of letting S27 go inactive. Per SEMI Regulations, inactive standards are still accessible, but have inactive watermark.

Motion: To let S27 go inactive and disband the TF.

By / 2nd: Chris Evanston/Cliff Greenberg

Discussion: Some contents are useful and may be salvaged. A question was raised on whether S27 could turn into a related information, but S2 already has guidance on evaluation report.

Vote: 10/1. Motion passed.

[Attachment – 12, SEMI 27 Report](#)

4.8 *S22 TF*

Sean Larsen said the TF will focus on safety interlock. It was reported teleconferences are being planned to discuss and coordinate with other task forces.

4.9 S8 (Ergonomics) TF

On behalf of Ron Macklin, Sean Larsen reported the TF proposes a Related Information (RI) pertaining to what should be considered in an SEMI S8 evaluation.

The TF also has a lengthy discussion on the topic of an aging workforce. It seems that this is becoming of topic of discussion within our circles (suppliers and users).

The TF requests for a new SNARF to address 7 additional areas that have been identified as needing some work or new development within the document.

Motion: To approve the SNARF for S8

By / 2nd: Eric Sklar/Bert Planting

Discussion: None

Vote: 9/0. Motion passed

[Attachment – 13, New SNARF Request for SEMI S8 - Spring 2016](#)

[Attachment – 14, S8_TF_committe_report_Spring 2016](#)

4.10 Control of Hazardous Energy (CoHE) TF

Sean Larsen presented. Highlights.

- Most of recent efforts have been in ICRC WG in regards to addendum to ANSI Z244 and an associated white paper
 - White paper development is still in process.
 - Coordination with ANSI Z244 committee will continue.
- Ballot ideas
 - Discussions related to a future line item ballot – there appears to be some easy areas for improvement.
 - There were some previous discussions of more significant changes, but would still have considerable work to be done to develop consensus.

[Attachment – 15, S2 CoHE](#)

4.11 Fire Protection TF

Eric Sklar reported ballot 5970 (S14) passed with an editorial change. For ballot 5969 (S2), LI1 failed and LI2 passed as balloted.

Other topics

- Application of S14 to events involving smoke or charring, but not flame
- Assessment of smoke risk in fabs
- Move Fire Detection & Suppression Sections to S14
- Inclusion of FPD, solar, solid state light sources, et al. equipment in the Scope of S14
- Further Alignment of S14 with S10

Future plans

- Handle ballot responses
- Continue work on topics not yet ready for ballot
- Future Line Item or Major Revision Ballot
- S2 Line Item Ballot Authorization (2016C5):
 - Reballot Insertion of screening flowchart and procedure for its use

[Attachment – 16, FireProtectionTFrpt_S2016_es07apr15a](#)

4.12 Energetic Materials TF

Eric Sklar reported the TF is having weekly and bi-weekly conference to discuss and work on SEMI draft document 5761A – Safety Guideline for use of Energetic Materials In Semiconductor R&D and Manufacturing Processes. The ballot is expected to be issued in cycle 5-16. For further details, see attachment below.

[Attachment – 17, EnergeticMatls TF Report - April 7 2016_es07apr16a](#)

5.0 Leadership and Liaison Reports

5.1 *Environmental, Health, and Safety Japan TC Chapter*

Supika Mashiro presented. Highlights.

- Leadership Changes
 - Seismic Protection TF
 - Naokatsu Nishiguchi/Screen Semiconductor Solutions
- Next Meeting
 - 13:30-17:00 (TBD), Wednesday, April 19, 2016 at SEMI Japan Office
- Ballot Result on December 18
 - Doc. 5556A: Line Item Revision to SEMI S2-0715, Environmental, Health, and Safety Guideline for Semiconductor Manufacturing Equipment, Revisions to §19 “Seismic Protection” (In Delayed Effective Date Format)
 - failed
 - Doc. 5947: Revision to SEMI S23-0813, with title change from “Guide For Conservation Of Energy, Utilities And Materials Used By Semiconductor Manufacturing Equipment” To “Guide For Energy, Utilities And Materials Use Efficiency Of Semiconductor Manufacturing Equipment”
 - Failed
- For Cycle 4, 2016
 - Doc. 5947A: Revision to SEMI S23, with title change from “Guide For Conservation Of Energy, Utilities And Materials Used By Semiconductor Manufacturing Equipment” To “Guide For Energy, Utilities And Materials Use Efficiency Of Semiconductor Manufacturing Equipment”
 - Major revision including purpose and scope to address energy efficiency
 - Doc. 5556A, Line Item Revisions to SEMI S2-0712, Environmental, Health, and Safety Guideline for Semiconductor Manufacturing Equipment Revisions Related to Section 19 Seismic Protection
- STEP Planning Working Group
 - STEP/ SEMI S2 was held on Friday, November 20 at the SEMI Japan, Tokyo (payed program)
 - 72 participants, including instructors
 - Overall feedback from the questionnaire was very positive
- Responsible Staff
 - Junko Collins, SEMI Japan, jcollins@semi.org

[Attachment – 18, JA EHS Liaison Report \(Taiwan\) 2016.03.22b](#)

5.2 *Environmental, Health, and Safety Taiwan TC Chapter*

Kevin Nguyen presented. Highlights

- “FPD Safety Subcommittee” was disbanded.
- “IC Equipment Safety TF” and “FPD Safety Subcommittee / Equipment Safety TF” were combined as one “Equipment Safety TF”
- 2016 SEMICON Taiwan EHS Forum will be held on Sept 7
 - Tentative Theme :
 - Disaster Recovery Experience Sharing
 - Energy Conservation
 - Topics coverage
 - BCP and BCM, the mechanism of resource share after disaster, the seismic protection for fab facility, the reality case share
- Discussion: These courses are appear to be from EHS Division. Supika Mashiro believes Taiwan has no knowledge on the distinction between EHS Division versus EHS Standards Committee.

[Attachment – 19, Taiwan EHS Liaison Report Mar 2016 r](#)

5.3 *RSC / Committee Leadership Report*

Sean Larsen reported. Highlights.

- There is a new version of the Procedure Manual published February 12, 2016
- Virtual Meetings
- Copyright issue for SML? Usage (critical to number of I&C standards) has been resolved.
- There is a new slide template that SEMI is asking us to use for all standards related activities. Contact staff if needed.
- SEMI is interested in developing standards related to flexible electronics and looking for participants in related industries to participate
 - Is thought that most of SEMI S documents can be used as is, but there may be some areas that could use some differences

[Attachment – 20, Co-chairs report](#)

5.4 *EHS Division Liaison*

Sanjay Baliga reported there was significant interest from China to conduct ½ day on Standards Education and ½ day on Compliance. EHS Standards members have been invited to join the task force. Teleconferences are being planned in coming weeks for discussion.

These seminars will have to be conducted in Mandarin and are planned for SEMICON China in 2017. Per Sanjay, if the seminar is conducted in parallel with China Semiconductor Industry Association (CSIA) event in late October or early November, 2016, the turnout would be great. However, it may be too early to pull it off with the right contents and speakers.

Discussion: Supika Mashiro recommended to use Working Group rather than Task Force, which can potentially cause confusion with Standards Task Force.

Cliff Greenberg commented the MESSC's charter was (15 years ago) to assist and oversee translation, but it is no longer in existence.

Sunny Rai said similar courses were conducted by him and Rich Kaplan about 10 years ago. He recommended Sanjay to contact Bettina Weiss, who was the SEMI Staff in charge at the time.

5.5 *Schedule Requests for SEMICON West Meetings*

Three days of meeting set appear to work well for everyone. For West, there will be two days of EHS Division meetings. Chris Evanston surveyed those in attendance with 8 choices of Standards meeting set. Base on committee's feedback, the majority was in favor of holding the Standards meetings on Tuesday, Wednesday, and Thursday during SEMICON West.

[Attachment – 21, Opinion Poll for scheduling](#)

6.0 **SEMI Staff Report**

Report was given by Kevin Nguyen. Highlights:

- SEMICON West Visitor Registration
 - Complimentary Expo Only badge is opened from March 15-May 6
 - Register Today!
 - <http://www.semiconwest.org/attend/registration>
- There are now 9 ballots cycle for 2016
 - http://www.semi.org/en/Standards/P_000788
- SEMI Standards Publications
 - Total SEMI Standards in portfolio: 962
- New Requirements/Process Reminders for TC Chapter Meetings from December 2014 Regulations
 - Standards Document Development Project Period
 - Project period shall not exceed 3 years (Regs 8.3.2)
 - If document development activity is found to be continuing, but cannot completed with the project period, TC Chapter may grant one-year extension at a time, as many times as necessary.

- SNARF Review Period
 - A submitted SNARF for a new, or for a major revision to an existing, Standard or Safety Guideline is made available to all members of a TC Chapter’s parent global technical committee for two weeks for their review and comment. (Regs 8.2.1)
 - If the SNARF is submitted at a TC Chapter meeting, the committee can review and approve, but the SNARF will need to be distributed for two weeks and then approved via GCS.
- 5 Year Review
 - SEMI S28-1011, Safety Guideline for Robots and Load Ports Intended for Use in Semiconductor Manufacturing Equipment
- 3 Year Status SNARF.
 - The following SNARF is coming up for the maximum 3 year project period.
 - Doc. 4975, Revision to SEMI S6, EHS Guideline for Exhaust Ventilation of Semiconductor Manufacturing Equipment (Line item revisions for addressing gas detectors and other concerns)
 - SNARF was approved on 4/1/2010
 - Discussion: Sean Larsen said 4975 was previously extended, but he was not sure.
 - **Action Item:** Kevin Nguyen to check minutes for the SNARF.

[Attachment – 22, Staff Report April 2016_EHS](#)

7.0 Old Business

7.1 SNARF Extensions (older than 3 years). This issue is addressed in section 6 (*3 Year Status SNARF*) above.

7.2 Disbanding Flow Limitation Task Force

Eric Sklar reported revision to SEMI S5-0310 - Safety Guideline for Sizing and Identifying Flow Limiting Devices for Gas Cylinder Valves, is completed.

Motion: To disband Flow Limitation Task Force

By / 2nd: Eric Sklar/Sean Larsen

Discussion: None

Vote: 4/0. Motion passed

8.0 New Business

8.1 Upcoming Ballot Authorizations

The following ballots will be issued for cycle 5 of 2016 for review at SEMICON West.

#	When	SC/TF/WG	Details
5761A	cycle 5-2016	Energetic Materials EHS Task Force	New Standard: Safety Guideline for Use of Energetic Materials in Semiconductor R&D and Manufacturing Processes
4683I	cycle 5-2016	S2 Chemical Exposure Task Force	Line Item Revision to SEMI S2-0715, Environmental, Health, and Safety Guideline for Semiconductor Manufacturing Equipment. Delayed Revisions Related to Chemical Exposure
5969A	cycle 5-2016	Fire Protection Task Force	Line Item Revision to SEMI S2-0715, Environmental, Health, and Safety Guideline for Semiconductor Manufacturing Equipment (Re: Fire Protection)

#	When	SC/TF/WG	Details
5681	cycle 5-2016	S6 Revision Task Force	Line Item Revision to SEMI S6, EHS Guideline for Exhaust Ventilation of Semiconductor Manufacturing Equipment
5917	cycle 5-2016	Ergonomics Task Force	Line Item Revisions to SEMI S8, Safety Guidelines for Ergonomics Engineering of Semiconductor Manufacturing Equipment. Addition of reference to a manual material-handling guide in SEMI-S8, Appendix 2, Lifting, Strength, and Materials Handling

Motion: To authorize ballots shown above for cycle 5 of 2016

By / 2nd: Bert Planting/Eric Sklar

Discussion: None

Vote: 8/0. Motion passed

9.0 Next Meetings

- The TC will meet on Thursday, July 14 in San Francisco, CA. See attachment for proposed schedule.

[Attachment – 23, West2016_EHS Schedule](#)

10.0 Action Item Review

Summary of action was reviewed by Kevin Nguyen. If any, these can be found in the New Action Items table 7 at the beginning of these minutes.

11.0 Adjourn

Meeting was adjourned at 2:00 PM

These minutes are respectfully submitted by:

Kevin Nguyen,
SEMI Standards Operations Manager
Phone: 408-943-7997
Email: knguyen@semi.org

Approved by:
Sean Larsen (Lam Research)
Chris Evanston (Salus Engineering)
Bert Planting (ASML)

Table 8 – Index of Attachment Summary

#	<i>Title</i>		<i>Title</i>
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2	4683H-LI1_Compiled Resp_TF inputs040516	14	S8_TF_committe_report_Spring 2016
3	5969_LI1+2_CompiledResponses_es07apr16a	15	S2 CoHE
4	5969ProceduralReview	16	FireProtectionTFrpt_S2016_es07apr15a
5	5970_L1..3_CompiledResponses_es07apr16a	17	EnergeticMatls TF Report - April 7 2016_es07apr16a
6	5970ProceduralReview	18	JA EHS Liaison Report (Taiwan) 2016.03.22b
7	2016 Spring MESSC minutes	19	Taiwan EHS Liaison Report Mar 2016 r
8	S6 Task Force_GH-040716	20	Co-chairs report
9	S2 Seismic Liaison TF Report Spring 2016 Rev	21	Opinion Poll for scheduling
10	S23 GTF Report US Spring meetings 2016	22	Staff Report April 2016_EHS
11	S10 taskforce report Spring 2016 MoM	23	West2016_EHS Schedule
12	SEMI 27 Report	24	

#1 Due to file size and delivery issues, attachments must be downloaded separately. A .zip file containing all attachments for these minutes is available at www.semi.org. For additional information or to obtain individual attachments, please contact Kevin Nguyen at the contact information above